

L Number	Hits	Search Text	DB	Time stamp
1	3	(thermopile and diaphragm) and dry adj3 etch	USPAT	2004/01/15 14:57
2	0	dry adj3 etch adj4 edp	USPAT	2004/01/15 14:58
3	0	dry adj3 etch near ehtylenediamine	USPAT	2004/01/15 14:58
4	0	dry near ehtylenediamine	USPAT	2004/01/15 14:59
5	0	RIE near ehtylenediamine	USPAT	2004/01/15 14:59
6	0	RIE adj3 ehtylenediamine	USPAT	2004/01/15 14:59
7	18144	reactive adj3 ion adj3 etching	USPAT	2004/01/15 14:59
8	190	(reactive adj3 ion adj3 etching) and EDP	USPAT	2004/01/15 15:00
9	98	((reactive adj3 ion adj3 etching) and EDP) and dry	USPAT	2004/01/15 15:06
10	702	thermopile and infrared	USPAT	2004/01/15 15:06
11	3	(thermopile and infrared) and DRIE	USPAT	2004/01/15 15:06
-	340	micromachined adj3 sensor	USPAT	2004/01/15 13:24
-	103	(micromachined adj3 sensor) and diaphragm	USPAT	2004/01/15 13:25
-	0	((micromachined adj3 sensor) and diaphragm) and dry adj3 etch?	USPAT	2004/01/13 15:11
-	0	((micromachined adj3 sensor) and diaphragm) and etch?	USPAT	2004/01/13 15:11
-	26	((micromachined adj3 sensor) and diaphragm) and dry	USPAT	2004/01/13 15:11
-	1	("5192240").PN.	USPAT	2004/01/15 10:19
-	1322	thermopile	USPAT	2004/01/15 13:25
-	82	thermopile and diaphragm	USPAT	2004/01/15 13:36
-	15	(thermopile and diaphragm) and dry	USPAT	2004/01/15 14:57